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Docket No.: C034932/0114785

**IN THE UNITED STATES PATENT AND TRADEMARK OFFICE**

In re Application of: )

Anthony R. A. KEANE, et al. )

Serial No.: 09/494,589 )

Filed: January 31, 2000 )

For: **POWER DELIVERY SYSTEM** )

Examiner: Marceau Milford

Art Unit: 2745

**RECEIVED**

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Technology Center 2600

July 9, 2004

Commissioner for Patents  
P.O. Box 1450  
Alexandria, VA 22313-1450

Sir:

**RESPONSE TO OFFICE ACTION**

This correspondence responds to the Office Action dated April 15, 2004 setting a three-month statutory period for response. Accordingly, this Response is timely filed with an executed certificate of mailing on or before July 15, 2004. See 37 C.F.R. §§ 1.8.

**REMARKS**

Claims 1-44 have been rejected under 35 U.S.C. §103(a) as being unpatentable over Turner et al (U.S. Patent No. 5,939,886, hereafter "Turner") in view of Williams, et al (U.S. Patent No. 5,472,561, hereafter "Williams. For the reasons which follow, Applicants respectfully traverse the rejection.

Turner discloses "a plasma monitoring and control method and system monitor and control plasma in an electronic device fabrication reactor by sensing the voltage of the radio frequency power that is directed into the plasma producing gas at the input to the plasma producing environment of the electronic device fabrication reactor." (Abstract). Turner further